

WHAT IS CLAIMED IS:

1. A piezoelectric element comprising:
a piezoelectric film sandwiched between a lower
electrode and an upper electrode,
5 wherein said lower electrode and/or said upper
electrode and said piezoelectric film comprise
perovskite oxide; and a contact interface between
said lower electrode and/or said upper electrode and
said piezoelectric film does not exist; and a region
10 where crystals of said lower electrode and/or said
upper electrode and crystals of said piezoelectric
film are mixed exists between said lower electrode
and/or said upper electrode and said piezoelectric
film.
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2. A piezoelectric element according to claim 1,
wherein said mixed region has a perovskite structure.
3. A piezoelectric element according to claim 1,
20 wherein said lower electrode, said upper electrode
and said piezoelectric film comprise perovskite oxide
manufactured by a sol-gel method.
4. A piezoelectric element according to claim 1,
25 wherein said lower electrode and said upper electrode
are represented by a general formula M^1RuO_3 (M^1 shows
at least one kind selected from Sr, Ba and Ca) or

$\text{Sr}_{(1-x)}\text{M}_{(x)}^2\text{CoO}_3$ (M^2 shows at least one kind selected from La, Pr, Sm and Nd; and $0 \leq x < 1$) and said piezoelectric film is represented by a general formula $\text{Pb}_{(1-x)}\text{La}_x(\text{Zr}_y\text{Ti}_{1-y})\text{O}_3$ (in the formula, $0 \leq x < 1$,
5 $0 \leq y \leq 1$).

5. An ink jet recording head comprising:
a pressure chamber communicated with an ink discharge port;
10 a vibrating plate provided in correspondence to said pressure chamber; and
a piezoelectric element provided in correspondence to said vibrating plate and having a piezoelectric film sandwiched between a lower
15 electrode and an upper electrode, wherein
ink in said pressure chamber is discharged from said ink discharge port by a change of volume in said pressure chamber caused by said piezoelectric element,
wherein said lower electrode and/or said upper
20 electrode and said piezoelectric film comprise perovskite oxide; and a contact interface between said lower electrode and/or said upper electrode and said piezoelectric film does not exist; and a region where crystals of said lower electrode and/or said
25 upper electrode and crystals of said piezoelectric film are mixed exists between said lower electrode and/or said upper electrode and said piezoelectric

film.

6. A method for manufacturing a piezoelectric element having a piezoelectric film sandwiched
5 between a lower electrode and an upper electrode, comprising, in the following order:
- a step for providing an electrode material for forming said lower electrode on a substrate;
 - a step for drying the electrode material;
 - 10 a step for providing a piezoelectric material to form said piezoelectric film on the electrode material;
 - a step for drying the piezoelectric material;
 - and
 - 15 a step for sintering the electrode material and the piezoelectric material.

7. A method according to claim 6, wherein a step for sintering the electrode material is not
20 performed after said step for drying the electrode material and before said step for providing the piezoelectric material for forming said piezoelectric film on the electrode material.

- 25 8. A method for manufacturing a piezoelectric element having a piezoelectric film sandwiched between a lower electrode and an upper electrode,

comprising, in the following order:

a step for providing a piezoelectric material for forming said piezoelectric film on said lower electrode;

5 a step for drying the piezoelectric material;

a step for providing an electrode material for forming said upper electrode on the piezoelectric material;

a step for drying the electrode material; and

10 a step for sintering the piezoelectric material and the electrode material.

9. A method according to claim 8, wherein a step for sintering the piezoelectric material is not performed after said step for drying the piezoelectric material and before said step for providing the electrode material for forming said upper electrode on the piezoelectric material.

20 10. A method for manufacturing a piezoelectric element in which at least an electrode and a piezoelectric film are laminated, comprising:

a step for providing a laminated structure of an electrode material for forming said electrode before sintering and a piezoelectric material for forming said piezoelectric film before sintering and;

a step for sintering said laminated structure.

11. A piezoelectric element comprising a piezoelectric film sandwiched between a lower electrode and an upper electrode,

wherein a contact interface between said lower
5 electrode and/or said upper electrode and said piezoelectric film does not exist; and a region where crystals of said lower electrode and/or said upper electrode and crystals of said piezoelectric film are mixed exists between said lower electrode and/or said
10 upper electrode and said piezoelectric film.